



PATENT  
8013-1074

2825

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of:

Hidemitsu AOKI et al.

Confirmation No. 6696

Serial No. 09/715,000

GROUP 2825

Filed November 20, 2000

Examiner Chuong A. Luu

IMPROVED SEMICONDUCTOR WAFER SURFACE  
AND METHOD OF TREATING A SEMICONDUCTOR  
WAFER SURFACE

PETITION FOR EXTENSION OF TIME

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 11, 2004

Sir:

The undersigned hereby petitions for an extension of time to respond to the Official Action of December 2, 2003 for one month to April 2, 2004.

Please charge the extension fee of \$110 to Deposit Account No. 25-0120. If this fee is insufficient, the Patent Office is hereby authorized to charge any additional extension fee to Deposit Account No. 25-0120. A duplicate copy of this sheet is enclosed.

A responsive paper is filed herewith.

Respectfully submitted,

YOUNG & THOMPSON

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